The UV absorption spectrum of SiH₃

P.D. Lightfoot^a, R. Becerra^b, A.A. Jemi-Alade^a and R. Lesclaux^a

* Laboratoire de Photophysique et Photochimie Moléculaire, Université de Bordeaux I, 33405 Talence Cedex, France

^b Instituto de Quimica-Fisica Rocasolano, CSIC, C/Serrano 119, 28006 Madrid, Spain

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Flash photolysis of CCl₄/SiH₄/N₂ mixtures in the far-UV gives rise to strong transient absorptions in the region 205-250 nm which are attributed to the first experimental observation of the $(\tilde{A}^2A_1 \leftarrow \tilde{X}^2A_1)$ transition of the SiH₃ radical.

1. Introduction

The spectroscopy of the SiH₃ radical is of considerable practical and theoretical interest. The radical plays an important role in chemical vapour deposition processes [1], and new techniques for its detection would be of great use in expanding the limited kinetic database on its reactions. In addition, SiH₃, isovalent with CH₃, provides a benchmark for the performance of electronic structure calculations of species containing second-row elements. Despite considerable experimental efforts over the years [2-4], the single-photon absorption spectrum of SiH_3 has escaped observation. This is largely due to the difficulty of producing monovalent silicon-based radicals - photolytic methods based on those classically used to produce carbon-based radicals invariably produce the thermodynamically favoured divalent silicon species, plus a stable molecule. Recently, however, Potzinger and co-workers have produced trialkyl(methyl, ethyl and n-propyl)silyl radicals via the mercury-sensitized photolysis of the corresponding silanes [5]. All three alkylsilyl radicals display strong, broad absorption bands peaking at around 260 nm, confirming earlier observations of the trimethylsilyl radical spectrum [6,7]. It was not possible to produce SiH₃ in the same manner, however, owing to polymer formation [5]. In recent years, SiH₃ has been successfully produced by the fast reaction of Cl atoms with SiH₄ [8,9], and has been detected by time-resolved LMR [9], resonance-enhanced multiphoton ionization (REMPI) [10,11], photoionization mass spectrometry [12] and timeresolved IR diode-laser spectroscopy [13]. Detectable quantities of SiH₃ have also been produced by the ArF laser photolysis of SiH₃Br and SiH₃I, although the quantum yields are low (around 0.1 for SiH₃Br) [13]. Extensive MRD-CI calculations by Olbrich [14] suggest that the first excited (Rydberg) state lies at 41860 cm⁻¹ and that this state is dissociative with respect to SiH₂ and H. The short lifetime of the excited state suggests in turn that the absorption band will be structureless and that the REMPI and LIF techniques will not be suitable in this wavelength region.

2. Experimental

The flash photolysis/UV absorption apparatus used in this study has been described in detail previously [15]. In short, it consists of a 1.5 ℓ cylindrical quartz cell, 70 cm long and 4.5 cm wide. Radicals are generated by the flash photolysis of slowly flowing gas mixtures and are detected by time-resolved UV absorption. The analysis beam is provided by a deuterium lamp. Experimental optical density-time profiles are collected on a digital storage oscilloscope, averaged, typically over 10-30 shots, and subsequently analysed by non-linear least-squares methods. The only difference between the experimental setup used in the present study and that previously described [15] is that the pyrex outer sleeve was removed from the spectrosil quartz flash lamp, so that far-UV rather than near-UV photolysis could be used.

Chlorine atoms were produced by the broad-band far-UV ($\lambda > 190$ nm) photolysis of CCl₄

$$\operatorname{CCl}_4 + h\nu(\lambda > 190 \text{ nm}) \rightarrow \operatorname{CCl}_3 + \operatorname{Cl},$$
 (P1)

$$\rightarrow$$
 CCl₂ + Cl + Cl. (P2)

In the present experiments, the CCl₄ molecule absorbs radiation in the far-UV, the absorption crosssection increasing from 17×10^{-20} cm² molecule⁻¹ at 220 nm to 144×10^{-20} cm² molecule⁻¹ at 190 nm [16], around where the ordinary quartz of the photolysis cell cuts off. The relative importance of photolysis channels (P1) and (P2) depends on the wavelength. At 253.7 and 213.9 nm, only (P1) is important [17,18], whereas the ratio of (P1) to (P2) is 2.8 at 184.9 nm and 0.33 at 163.3 nm [17,18]. It is, thus, expected that (P1) will largely dominate in the present experiments, although small amounts of CCl₂ will be produced via (P2).

All experiments were performed at room temperature and atmospheric pressure. Reagent concentrations were, in units of molecule cm⁻³: SiH₄ (0.3– $12) \times 10^{16}$; CCl₄ (0.9–6.7) $\times 10^{16}$; balance N₂. Nitrogen (AGA, > 99.5%), silane (l'Air Liquide, electronic grade) and carbon tetrachloride (Prolabo, normapur grade) were used without further purification.

3. Results

Photolysis of CCl_4/N_2 mixtures produced weak absorptions in the region 210–240 nm; the wavelength dependence of the initial absorption was characteristic of the spectrum of the CCl_3 radical in this region [19]. In the absence of other gases, the radicals produced in the photolysis will be removed by reaction among themselves:

$$CCl_3 + CCl_3 + M \rightarrow C_2Cl_6 + M, \qquad (1)$$

 $CCl_3 + Cl + M \rightarrow CCl_4 + M, \qquad (2)$

$$Cl+Cl+M \to Cl_2 + M . \tag{3}$$

The CCl_3 absorptions followed approximately second-order kinetics, but with a rate of disappearance which was significantly faster than that expected on the basis of the CCl₃ self-reaction alone. The association reaction of CCl₃ with Cl atoms is around 20 times faster than the self-reaction at room temperature and atmospheric pressure [19], so this observation is consistent with the presence of Cl atoms in the system. The initial absorption due to CCl₃ varied linearly with CCl₄ concentration over the range (0.9– $6.7) \times 10^{16}$ molecule cm⁻³; typical initial CCl₃ concentrations were (1–4)×10¹³ molecule cm⁻³.

Silane does not absorb above 170 nm [20] and so is unaffected by the photolysis radiation from our flash lamp. In the presence of SiH_4 , the following additional reactions may occur:

 $Cl+SiH_4 \rightarrow HCl+SiH_3$, (4)

 $CCl_3 + SiH_3 \rightarrow products$, (5)

 $SiH_3 + SiH_3 \rightarrow Si_2H_6$ [21]. (6)

Reaction (4) is known to be very fast $(k_4/\text{cm}^3 \text{ molecule}^{-1} \text{ s}^{-1} = 3 \times 10^{-10} [8,9])$ and will be the only loss process for Cl atoms in the presence of excess SiH₄. The abstraction reaction of CCl₃ with SiH₄ to form SiH₃ is expected to be negligibly slow in these experiments – the analogous reaction of CH₃ has a rate constant of 1.0×10^{-17} at 298 K [22] and CCl₃ would be expected to be even less reactive.

On adding small concentrations of SiH₄ to the photolysis mixture, we observed strong transient absorptions in the region 205-250 nm, with an apparent maximum at around 215 nm. At this wavelength, which is near to the maximum of the CCl₃ spectrum at 211 nm [19], the peak absorptions were around a factor three larger than those observed in the absence of SiH₄; at longer wavelengths, this ratio was larger. The largest contribution of CCl₃ to the initial absorption was at the shortest wavelengths, where it approached 40%. An optical density profile showing the main features of the transient behaviour is shown in fig. 1a. At all wavelengths, a rapid reaction, giving rise to a residual absorption after around 20 ms, was observed. The residual absorption, seemingly corresponding to a stable product, was around 25% of the peak absorption at wavelengths of 215 nm and longer, but somewhat stronger at shorter wavelengths. Initial absorptions were extracted from second-order fits to decay traces collected on a 2 ms timescale, as shown in fig. 1b. Over such short times, less than half of the initial absorption had decayed.

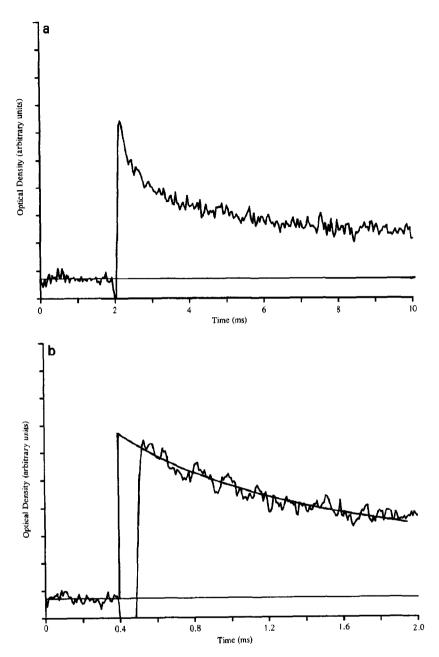


Fig. 1. (a) Representative optical density-time profile following the flash photolysis of a $CCl_4/SiH_4/N_2$ mixture. Reagent concentrations are (in units of 10¹⁶ molecule cm⁻³): [CCl_4]=6.72; [SiH_4]=0.80; [N_2] to 1 atm. Monitoring wavelength 230 nm. (b) Typical decay trace used to extrapolate to t=0. The solid line represents a simple second-order fit to the data. Monitoring wavelength 230 nm. Reagent concentrations are (in units of 10¹⁶ molecule cm⁻³): [CCl_4]=6.72; [SiH_4]=0.40; [N_2] to 1 atm.

In addition, the back extrapolation of the transient absorption over the 150 μ s post-flash dead-time of our detection system amounts to only around 5% of the total initial absorption, and errors due to kinetic uncertainties are very small. Due to the strong UV cross-sections of CCl_4 at the shorter wavelengths [16] and the weak transient absorption at the longer wavelengths, it was not possible to cover the whole

of the observed absorption band with the same CCl₄ concentration. Partial spectra (i.e. initial absorption versus wavelength) were recorded at four different CCl_4 concentrations over the range (0.9-6.72) $\times 10^{16}$ molecule cm⁻³. The average of these relative spectra, normalized to the initial absorption at 215 nm and corrected for the contribution of CCl₃, are shown in fig. 2; no systematic dependence of the shape of the spectra on CCl₄ concentration was observed. The initial absorption at 230 nm varied approximately linearly with $[CCl_4]$. The wavelength dependence of the residual absorption is shown in fig. 3. No variation in the strength of the initial absorption or the subsequent kinetics was observed on varying the SiH₄ concentration over the range $(0.31-12) \times 10^{16}$ molecule cm^{-3} .

Additional experiments were attempted in which

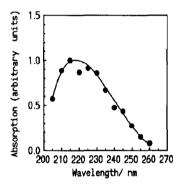


Fig. 2. Relative spectrum, normalized to 215 nm, of the initial absorbance produced on photolyzing $CCl_4/SiH_4/N_2$ mixtures at four different CCl_4 concentrations over the range (0.90–6.72) $\times 10^{16}$ molecule cm⁻³.

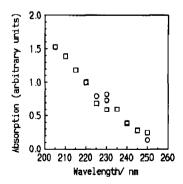


Fig. 3. Relative spectra of the residual absorption produced on photolyzing $CCl_4/SiH_4/N_2$ mixtures. CCl_4 concentrations (in units of 10^{16} molecule cm⁻³) are: (\bigcirc) 6.72 and (\square) 1.79. In each case, the spectrum in normalized to the value at 220 nm.

it was planned to photolyze molecular chlorine in the presence of silane. However, adding SiH₄ to a flowing gas mixture of Cl₂ and N₂ consumed the Cl₂ via a thermal reaction within the residence time of the gases in the cell (around 30 s), as observed by its absorption at 330 nm [16], even at concentrations of SiH₄ and Cl₂ below 10^{16} molecule cm⁻³.

4. Discussion

There is strong evidence supporting the attribution of the transient absorptions observed in the present experiments to the SiH₃ radical. Firstly, the chlorine atoms produced in the photolysis of CCl₄ will react with SiH₄ to produce SiH₃. The production of the absorbing species is complete within the postflash dead-time of our detection system (150 µs), even at concentrations of SiH₄ as low as 0.31×10^{16} molecule cm^{-3} , which is compatible with a rate constant $k_4 > 3 \times 10^{-12}$ cm³ molecule⁻¹ s⁻¹. In order for our perceived initial absorption to be in fact due to products of radical-radical reactions (e.g. reaction (5)), such reactions would have to be essentially completed within 150 µs, indicating a rate constant of around 3×10^{-10} cm³ molecule⁻¹ s⁻¹ for a typical initial radical concentration of 4×10^{13} molecule cm^{-3} . Such a rate constant appears unreasonably large for a reaction between two polyatomic free radicals.

The peak cross-section for (CH₃)₃Si is around 3×10^{-17} cm² molecule⁻¹ [5], i.e. around twice as large as the peak absorption cross-section of the CCl₃ radical at 211 nm [19]. Our observations are consistent with a SiH₃ absorption band which is considerably stronger than that of CCl₃. Assuming that only photolysis channel (P1) operates, we conclude that $([SiH_3]/[CCl_3])_{t=0}=1.0$. In this way, we can estimate an *approximate* peak absorption cross-section for SiH₃ of 2.4×10^{-17} cm² molecule⁻¹ at 215 nm. Of course, if photolysis channel (P2) were important, then this method would underestimate the initial SiH₃ concentration. Assuming a worst case of (P1)/(P2) = 2.8 (see above), we find that $([SiH_3]/$ $[CCl_3]_{t=0}=1.7$ and $\sigma(SiH_3, 215 \text{ nm})/\text{cm}^2$ molecule⁻¹= 1.4×10^{-17} .

Finally, but importantly, high-level ab initio calculations by Olbrich [14] predict that the vertical transition of the $(\tilde{A}^2 A_1 \leftarrow \tilde{X}^2 A_1)$ transition in SiH₃ lies at 239 nm. The electronic ground state of SiH₃ is pyramidal, whereas the excited state is planar and the absorption band should display significant intensity to either side of the vertical transition, as is observed. The band is also predicted to be diffuse, due to the short lifetime of the excited state with respect to dissociation, again in good agreement with our observations.

The strong residual absorptions observed in these experiments can be attributed to species formed in post-flash reactions. For example, the $Cl_3CSiH_3^*$ species formed in reaction (5) will contain around 90 kcal mol⁻¹ excess energy [23], enough to produce silylenes if not collisionally stabilized

 $Cl_3CSiH_3^* + M \rightarrow Cl_3CSiH_3 + M$, (5a)

$$Cl_3CSiH_3^* \rightarrow Cl_3CSiH + H_2$$
, (5b)

 \rightarrow CHCl₃+SiH₂, (5c)

$$\rightarrow CCl_2 + SiH_3Cl.$$
 (5d)

Such elimination processes are well known in the pyrolysis of alkylsilanes [24]. Cl₃CSiH could go on to produce the silene Cl₂C=SiHCl via a 1,2 Cl-atom shift, and silenes are known to absorb strongly in the far-UV [25]. Other possible contributors to the residual absorption are Cl₃CSiH₃ and unsaturated products of the reactions of the small quantities of CCl₂ produced by photolysis via reaction (5d). Such unknowns in the kinetics of the systems should not affect the initial absorption, however. The extrapolation of the optical density to t=0 is very short with respect to the subsequent timescale of its decay and any errors introduced by uncertainties in the kinetics can only be of the order of a few percent.

The presence of a contribution from CCl₃ to the initial absorption increases the uncertainty of our measurements, but only slightly, as this contribution was never more than 40%, and usually significantly less. Nevertheless, a convenient, clean, photolytic source of SiH₃ radicals has yet to be identified – photolysis of silyl halides produces SiH₃ in low yields [13], generation of Cl atoms by the photolysis of molecules other than Cl₂ leads to the unavoidable production of a second radical and SiH₄/Cl₂ mixtures are subject to thermal chain reactions.

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